

**Amendments to the Specification:**

Please amend paragraph [0015] as follows:

[0015] The invention provides a system and method for high-resolution multi-perspective SEM detection of high aspect ratio ~~ratio~~ holes (HAR mode).

Please amend paragraph [0030] as follows:

[0030] Once electrons are ~~emitted/scattered~~ emitted/scattered as a result as an interaction between the primary beam and the inspected object, they are attracted, due to a strong electrostatic field, towards the in-lens detector and to the aperture of that detector. The strength of the electrostatic field determines which secondary electrons are attracted to the in-lens detector and which are attracted to the aperture of the in-lens detector.

Please amend paragraph [0052] as follows:

[0052] Method 200 can be implemented at various tilt states. Whereas a tilt state is characterized by the tilt angle (that can range between about ~~very~~ very small angles to angles that are slightly smaller than 90 degrees) between the primary electron beam and the inspected area.